

Application/Control No.	Applicant(s)/Patent under Reexamination	
10/821,260	SNYDER ET AL.	
Examiner	Art Unit	
Teena Mitchell	3771	

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Class	Subclass	Date	Examiner
128	200.23 203.15 203.19 203.21	1/5/2008	ТКМ
128	203.12	1/5/2008	ТКМ
128	200.14	1/5/2008	TKM
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INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
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